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OIPE 20 2004 Line:

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

re: Application of:

Hsiu Ouyang

Group Art Unit: 2822

Serial No.:

10/685,127

Examiner: Thomas, Toniae M.

Filed:

Oct. 14, 2003

In Response to Office Action

Dated: Oct.

Oct. 6, 2004

For:

Etching Method for Forming a Square Cornered

Polysilicon Wordline Electrode

Attorney Docket No.: 67,200-1097

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the united States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Date: Dec. 13, 2004

RESPONSE TO OFFICE ACTION

Commissioner for Patents Alexandria, VA 22313-1450

Dear Sir:

In response to an Office Action mailed Oct. 6, 2004 of a restriction requirement imposed by the Examiner, the Applicants hereby elect with traverse the prosecution of Group I, method claims 1-20.